



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Basol et al. Serial No.: 10/654,542 Filed: September 2, 2003 Title: Constant Low Force Wafer Carrier For Electrochemical Mechanical Processing And Chemical Mechanical Polishing	Group Art Unit: 1753 Examiner: Not yet assigned Docket: NT-260 -US
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INFORMATION DISCLOSURE STATEMENT

US PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	
EM	AA	6,447,379	Sep., 2002	Gromko et al.	Copy Enclosed
EM	AB	6,443,824	Sep., 2002	Shendon et al.	Copy Enclosed
EM	AC	6,080,050	Jun., 2000	Chen et al.	Copy Enclosed
EM	AD	5,916,015	Jun., 1999	Natalicio	Copy Enclosed
EM	AE	5,423,716	Jun., 1995	Strasbaugh	Copy Enclosed

FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant		

OTHER DOCUMENTS

Examiner Initials	Cite No.			Translation

Examiner Signature	/Eileen Morgan/	Date Considered	06/21/2006
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